

# MetPrep Preparation Procedure - No150



## Reaction bonded Silicon Carbide

	Surface	Abrasive	Pressure		Speed – Dir	Time
Primary Grinding Stage	Fixed Diamond	20 µm MB	Psi	N	500 – Comp	Until Planar
			5	25		

	Surface	Abrasive	Pressure		Speed – Dir	Time
Additional Grinding Stages	Fixed Diamond	10 µm RB	Psi	N	500 – Comp	6 mins
			5	25		
	Planocloth	6 µm (WB) PCD Diamond	5	25	250 – Comp	4 mins

	Surface	Abrasive	Pressure		Speed – Dir	Time
Polishing Stage	Planocloth	1 µm (WB) PCD Diamond & 0.06 µm Silco	Psi	N	100 – Contra	10 mins
			5	25		